WEST Search History

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DATE: Wednesday, June 07, 2006

Hide?	Set Name	Query	Hit Count
		DB=PGPB; PLUR=YES; OP=ADJ	
☐	L9	((semiconductor wafer) and controlling and $ratio and drying and gas).clm.	0
☐	L8	((semiconductor wafer) and controlling and $ratio anddrying and gas).clm.	0
☐	L7	((semiconductor wafer) and controlling and $ratio with drying and gas).clm.	0
		DB=PGPB,USPT; PLUR=YES; OP=ADJ	
☐	L6	(semiconductor wafer) and controlling and $ratio with drying	41
☐	L5	(semiconductor wafer) with processing with controlling with $ratio with drying	0
		DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ	
☐	L4	(semiconductor wafer) with processing with controlling with $ratio with drying	1
		DB=PGPB,USPT; PLUR=YES; OP=ADJ	
☐	L3	(semiconductor wafer) with processing with controlling with $ratio with drying	0
☐	L2	(semiconductor wafer) with processing with controlling with (gas ratio) with drying	0
☐	L1	(semiconductor wafer) with processing with controlling with (gas ratio) with drying with nitrogen with alcohol	0

END OF SEARCH HISTORY